

AMENDMENT OF THE CLAIMS

Please amend the claims as follows:

1-3 (Canceled).

4. (Currently Amended) The vacuum deposition apparatus according to claim [[1]]
18, wherein the susceptor is made of a quartz material.

5. (Currently Amended) The vacuum deposition apparatus according to claim [[1]]
18, wherein the groove has a polygonal configuration.

6. (Currently Amended) The vacuum deposition apparatus according to claim [[1]]
18, wherein a bottom face of the groove has a curved configuration.

7. (Currently Amended) The vacuum deposition apparatus according to claim [[1]]
18, wherein a bottom face of the groove includes an incline plane and a perpendicular plane.

8. (Currently Amended) The vacuum deposition apparatus according to claim [[1]]
18, wherein the groove has a V-shaped configuration.

9. (Canceled)

10. (Previously Presented) The vacuum deposition apparatus according to claim 4, wherein the susceptor is in direct contact with the glass substrate when the glass substrate is heated.

11-15. (Canceled).

16. (Currently Amended) The vacuum deposition apparatus according to claim [[1]] 18, wherein the susceptor is rectangular.

17. (Canceled)

18. (New) A vacuum deposition apparatus having a process chamber, comprising:
a susceptor for heating a glass or quartz substrate, all four edges of the susceptor acting as a sliding portion on which to slide the glass or quartz substrate to a stopped position by stopping pins placed on the sliding portion, the susceptor having a raised perimeter portion structured to accommodate sliding of the glass substrate without incurring contact of the glass or quartz substrate with a build up of vacuum deposited material on the raised perimeter portion of the susceptor;

means for positioning the glass or quartz substrate into contact with the susceptor at a non-parallel angle to a top surface of the susceptor and for permitting edges of the glass or quartz substrate to slide along a portion of the susceptor toward stopping pins until the glass or quartz substrate is substantially parallel with the susceptor;

wherein the susceptor includes a groove formed in all four edges of said raised perimeter portion at a location of the stopping pins to receive vacuum deposited material and thereby minimize formation by the vacuum deposited material of a film on the raised perimeter portion of the susceptor, and

wherein a length of said raised perimeter portion, measured from said groove, to the recessed center portion of the susceptor is about 10 mm to minimize breakage of the glass or quartz substrate by preventing a severe bend of the glass or quartz substrate during transfer of the glass or quartz substrate to the susceptor.